

## PATENT APPLICATION

Sheet 1 of 2

FORM PTO-1449  LIST OF PATENTS AND PUBLICATIONS FOR APPLICANT'S INFORMATION DISCLOSURE STATEMENT  (Use several sheets if necessary)	ATTY. DOCKET NO. <b>200309716-1</b>	APPLICATION NO. <b>16/677539</b>	CONFIRMATION NO.
	APPLICANT <b>Michael Monroe t al.</b>		
	FILING DATE <b>H rewith</b>	GROUP <b>Unkn.</b>	

## REFERENCE DESIGNATION

## U.S. PATENT DOCUMENTS

EXAMINER INITIAL		DOCUMENT NUMBER	PUBLICATION DATE	NAME	Pages, Columns, Lines Where Relevant Passages or Figures Appear
<i>De</i>	1A	5,583,688	12/1996	Hornbeck	—
	1B	5,650,881	07/1997	Hornbeck	—
	1C	5,919,548	07/1999	Barron et al.	—
	1D	6,025,951	02/2000	Swart et al.	—
	1E	6,121,552	09/2000	Brosnihan et al.	—
	1F	6,396,368	05/2002	Chow et al.	—
	1G	6,440,766	08/2002	Clark	—
	1H	6,469,330	10/2002	Vigna et al.	—
	1I	6,480,320	11/2002	Nasiri	—
	1J	6,523,961	02/2003	Ilkov et al.	—
<i>De</i>	1K	20020039470	04/2002	Braun et al.	—

## FOREIGN PATENT DOCUMENTS

		DOCUMENT NUMBER	PUBLICATION DATE	NAME OF PATENTEE OR APPLICANT	Pages/Columns/Lines Where Relevant Passages/Figures Appear	Check if Translation attached
<i>De</i>	1L	EP1093143	04/2001	Lucent Tech Inc.	—	—
	1M	JP2000314634	07/2001	Lucent Tech Inc.	—	—
	1N					
	1O					
	1P					

## OTHER REFERENCES (including Author, Title, Date, Pertinent Pages, etc.)

<i>De</i>	1Q	J.H. Smith et al., "Material and Processing Issues for the Monolithic Integration of Microelectronics with Surface-Micromachined Polysilicon Sensors and Actuators" SPIE, October 1995, Pages 1-10.
<i>De</i>	1R	Oliver Brand, "CMOS-based MEMS/DTU PhD Course/Topics in Microelectronics", Physical Electronics Laboratory, ETH Zurich, <a href="http://www.iqe.ethz.ch/pel">http://www.iqe.ethz.ch/pel</a> , slides A-2 through A-36.
<i>De</i>	1S	J.H. Smith et al., "Embedded Micromechanical Devices for the Monolithic Integration of MEMS with CMOS", 1995 IEEE, Pages 609-612.
EXAMINER	<i>De</i>	DATE CONSIDERED <b>150V-024</b>

## PATENT APPLICATION

Sheet 2 of 2

<b>FORM PTO-1449</b>  <b>LIST OF PATENTS AND PUBLICATIONS FOR APPLICANT'S INFORMATION DISCLOSURE STATEMENT</b>  (Use several sheets if necessary)	ATTY. DOCKET NO.	APPLICATION NO.	CONFIRMATION NO.
	200312474-1		
	APPLICANT		
	Michael Monroe et al.		
	FILING DATE	GROUP	
	Herewith	Unkn.	

## REFERENCE DESIGNATION

## U.S. PATENT DOCUMENTS

EXAMINER INITIAL		DOCUMENT NUMBER	PUBLICATION DATE	NAME	Pages, Columns, Lines Where Relevant Passages or Figures Appear
Dh	2A	20030034535	02/2003	Barenburg et al.	—
	2B	5,485,304	01/1996	Kaeriyama	—
	2C	5,631,782	05/1997	Smith et al.	—
	2D	5,646,768	07/1997	Kaeriyama	—
	2E	5,703,728	12/1997	Smith et al.	—
	2F	6,038,056	03/2000	Florence et al.	—
Dh	2G	6,323,982	11/2001	Hornbeck	—
	2H				
	2I				
	2J				
	2K				

## FOREIGN PATENT DOCUMENTS

		DOCUMENT NUMBER	PUBLICATION DATE	NAME OF PATENTEE OR APPLICANT	Pages/Columns/Lines Where Relevant Passages/Figures Appear	Check if Translation attached
	2L					
	2M					
	2N					
	2O					
	2P					

## OTHER REFERENCES (including Author, Title, Date, Pertinent Pages, etc.)

Dh	2Q	Bikram Baidya et al., "Layout Verification and Correction of CMOS-MEMS Layouts", Carnegie Mellon University, Pittsburgh.
Dh	2R	Jeffrey D. Zahn et al., "A Direct Plasma Etch Approach to High Aspect Ratio Polymer Micromachining With Applications in Biomems and CMOS-MEMS, 2002 IEEE, pgs. 137-140.
Dh	2S	Jim Hunter et al., "CMOS friendly MEMS manufacturing process", 1998 IEEE, pgs. 103-104.

EXAMINER

Dh

DATE CONSIDERED

Nov-04